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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Pan et al.

Serial No.: 09/614,113

Filed: July 12, 2000

For: TECHNIQUE FOR ELIMINATION
OF PITTING ON SILICON SUBSTRATE
DURING GATE STACK ETCH

Confirmation No.: 1710

Examiner: D. Deo

Group Art Unit: 1765

Attorney Docket No.: 2269-2915.3US
(96-0149.02/US)

CERTIFICATE OF MAILING

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6/4/2003
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Name (Type/Print)

AMENDMENT UNDER 37 C.F.R. §1.116

Mail Stop AF
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are filed in response to the Examiner's remarks in the Final Office Action mailed April 8, 2003, the three-month shortened statutory period for response to which expires on July 8, 2003. This response is submitted on or before two months from the mailing date of the Final Office Action.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.